



June 20, 2001

Page 1 of 1

Form PTO-1449 U.S. Department of Commerce
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INFORMATION DISCLOSURE
STATEMENT BY APPLICANT

Atty. Docket No.	Serial No.
54197-237098	09/876,459
Applicant	
TRAVIS A. LEMKE	
Filing Date	Group
June 7, 2001	

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
TSS	3,392,493	07/1968	Hofmann et al.	—	—	
TSS	3,412,325	11/1968	Soderling	—	—	
TCS	3,719,090	03/1973	Hathaway	—	—	
TCS	4,382,173	05/1983	Howard-Leicester	—	—	
TCS	4,910,155	03/1990	Cote et al.	—	—	
TCS	4,977,929	12/1990	Chinnock et al.	—	—	
—	5,272,027	12/1993	Dillenbeck et al.	—	—	
—	5,293,893	03/1994	O'Dougherty	—	—	
—	5,340,370	08/1994	Cadien et al.	—	—	
—	5,364,510	11/1994	Carpio	—	—	
—	5,447,056	09/1995	Foote	—	—	
—	5,490,611	02/1996	Bernosky et al.	—	—	
—	5,522,660	06/1996	O'Dougherty et al.	—	—	
—	5,632,960	05/1997	Ferri, Jr. et al.	—	—	
—	5,647,989	07/1997	Hayashi et al.	—	—	
—	5,664,990	09/1997	Adams et al.	—	—	
—	5,755,614	05/1998	Adams et al.	—	—	

FOREIGN PATENT DOCUMENTS

Name	Document Number	Date	Country	Class	Subclass	Translation Yes/No
—	0 605 395	6 July 1994	EP	—	—	
—	0 714 054	29 May 1996	EP	—	—	
—	62 11520	7 October 1985	JP	—	—	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

—	Adams, et al., <i>CMP Slurry Reprocessing</i> , 6 pp. <i>X Cited on sheet 1</i>
—	Philipossian, et al., "An Overview of Current Issues and Future Trends in CMP Consumables," Proceedings of the First CMP-MIC Conference, February 1996, pp. 13-19. <i>X</i>
—	J. P. Bare, "Improved Analytical Technique for Metal CMP Slurry," Proceedings of 2 nd CMP-MIC Conference, February 1997, pp. 405-408. <i>X</i>

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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NOTE: *X Cited on sheet 1* *Sheet 2 of 3*